Solid-state bolometric sensors

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Astroparticles Solid-State Detectors (ASSD)

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Basic principles of calorimeters



- The only relevant parameter for the energy absorber is the heat capacity C.
- The thermal conductance to the bath G enables the temperature recover.

signal
$$\Delta T = E/C$$
 $\tau = C/G$ relaxation time

Dielectric diamagnetic materials are preferred

$$\frown$$
 C \propto (T/ Θ_{D})³ (Debye Law)

Semiconductor thermistors

Doped semiconductors close to the Metal to Insulator Transition (MIT)

At low temperatures (< ~10 K), the resistivity is given by: (Variable Range Hopping with Coulomb gap conduction regime)

 $\rho(T) = \rho_0 \exp[(T_0/T)^{1/2}]$

 $T^{}_{0}$ depends on the doping level \rightarrow it fixes $\rho^{}_{0}$ and the sensitivity

Two main types:

- Neutron Transmutation Doped (NTD) Ge thermistors
- Ge crystal exposed to neutron bombardment
- Neutron capture and subsequent β decay and electronic capture produce p and n doping
- Neutron dose fixes net doping
- MIT: 6 x 10 ¹⁶ cm ⁻³

$\begin{array}{c|c} \hline \mathbf{C} & 10^4 \\ \mathbf{M} & \mathbf{example} \\ 10^2 \\ \hline 20 & 100 \\ \mathbf{T} \ [\mathrm{mK}] \end{array}$

NTD Ge

200

10⁶

② Si-implanted thermistors

- Standard microelectronic technology
- Implantation of P, As (n-doping), B (p-doping)
- MIT (Si:P): 3 x 10 ¹⁸ cm ⁻³

Neganov-Trofimov-Luke (NTL) effect

Charge-to-heat transducers exploiting the Neganov-Trofimov-Luke effect for light detection in rare-event searches

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Nuclear Inst. and Methods in Physics Research, A 940, 320–327 (2019)

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Large area Ge light detectors

Electric voltage used to amplify charge signal



Copper holder

Neganov-Trofimov-Luke (NTL) effect

Calibration is done with X-rays, background cosmic rays etc.



(a) Energy spectrum of an X-ray $^{55}{\rm Fe}$ source, irradiating the NTLLD1 detector.



(c) LED pulses (bursts) of different intensities delivered to the detector (NTLLD2), which records signal of x_0 amplitude (uncalibrated). Each peak has $(x_0)_i$ mean and σ_i^2 width.

Most of the tests were done with photons from infrared LED setup



Transition edge sensors (TES)

- TES is a superconducting film kept around T_c
- It exploits the steep temperature dependence of the resistance in these conditions



if we define the sensitivity as $A \equiv |d \log R/d \log T|$ $A \cong 10 \text{ for ST}$ $A \cong 1000 \text{ for TES}$ Low impedance thermistors $\Rightarrow SQUID \text{ readout}$

Much higher S/N ratio with respect to ST

Superconductor-Insulator transition (SIT)

- It is important to have low T_c in order to operate detectors at low temperatures
- Only a few SCs have $T_c < 110 \text{ mK}$
- Sometimes it is useful to tune T_c at a desired value

Nb, Si, Percentage of Nb in the x=0.076 104 alloy of Nb and Si drastically changes the transport properties 10² Insulator ρ (Ωcm) 10⁰ Both metallic and insulating states are possible 10-2 Superconductor These films can be used both 10-4 for low impedance and high 3.0 0.5 1.0 1.5 2.0 2.5 3.5 0.0 impedance TESs Temperature (K)

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Stefanos Marnieros, PhD thesis, 1998

Different ways to tune T_c : Film thickness, composition, annealing temperature x=0.078 =0.080

=0.083 =0.090

(=0.13)

4.0

Lab facilities

Coevaporation system



Dilution fridge



Arrays of TESs



- Radiation absorber
- Thermometer
- Thermally isolated holder

204-pixel array of amorphous $Nb_{0.14}Si_{0.86}$ with a meander structure



High-impedance NbSi TES sensors for studying the cosmic microwave background radiation

C. Nones et al., Astronomy & Astrophysics 548, A17 (2012)

Geometry name	<i>d</i> [µm]	Gap [<i>µ</i> m]	Surface [mm ²]
Thin horizontal (A)*	10	10	1.51
Thin circular (B)	10	10	1.55
Thick vertical (C)	30	10	2.25
Thin vertical (D)	10	10	1.54
Medium vertical	15	5	2.31
			9



High impedance thermistors

High Impedance TES Bolometers for EDELWEISS

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High impedance allows readout with JFET electronics

Calibration of a 200 g NbSi -Ge bolometer using ⁷¹Ge activation by neutrons. The Ge crystal was biased at 66 V for NTL amplification.

Journal of Low Temperature Physics (2023) 211:214–219

High aspect ratio meander: Line length to line width : $10^3 - 10^4$

Composition : Nb_{0.132}Si_{0.868}



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Nb_xSi_{1-x} spiral Al grid



QUBIC installation at Argentina



TES pixel array



250 pixel array for QUBIC







Deep silicon etching to realise the suspended membranes. High thermal decoupling to optimise signal/noise



TES pixel array











Phase diagram of Y_xSi_{1-x}

Composition-dependence of transport properties in YSi thermometric films

L. H. H. To · S. Sengupta · F. Pallier · L. Bergé · L. Dumoulin · S. Marnieros · C. Marrache-Kikuchi.

Journal of Low Temperature Physics, 209, 1104–1110 (2022)

Superconductor-Insulator transition with varying composition



Resistance characteristics of insulating a-Y₂₀Si₈₀ film (thickness : 30 nm)



Highlights

Semiconductor thermistors and detectors



Transition edge sensors with superconductors



Copper holder



Study of new materials